

Notice of References Cited		Application/Control No.	Applicant(s)/Patent Under Reexamination	
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Examiner		Art Unit		Page 1 of 1
Hugh Jones		2128		

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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*	B	US-2008/0021677	01-2008	Buxton et al.	702/184
*	C	US-6,847,855	01-2005	Poeppel, Gerhard	700/110
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NON-PATENT DOCUMENTS

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	U	Abercrombie et al. (inventors), Method for Calculating High-Resolution Wafer Parameter Profiles; 2004 IEEE/SEMI Advanced Semiconductor Manufacturing Conference, pp. 119-123.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.